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| INFORMATION DISCLOSURE CITATION (Use several sheets if necessary) | | | | Applicant: Seilchi HAYASHI, et al. | | Filing Date: May 9, 2001 | |
| | | | | Group: 2882 | | | |
| U.S. PATENT DOCUMENTS | | | | | | | |
| Examiner Initial | | Document Number | Date | Name | Class | Subclass | Filing Date If Appropriate |
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| FOREIGN PATENT DOCUMENTS | | | | | | | |
| | | Document Number | Date | Country | Class | Subclass | Translation Yes No |
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| TRANSLATION KEY: * English Abstract. ^F Concise statement of relevance provided in foreign search report. ^C Concise statement of relevance provided in specification. ^S Concise statement of relevance provided in IDS. ^P Relevant portion of reference translated. ^O English abstract only - copy of reference in pct search. | | | | | | | |
| OTHER INFORMATION DISCLOSURE CITATIONS (Including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | |
| Not considered No copy | | 1997 - X-ray Reflectometer for the Diagnostics of Thin Films During Growth, U. Niggemeier, K. Lischka, W. M. Plotz and V. Holy, Journal of Applied Crystallography, Volume 30, Pages 905-908 | | | | | |
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| EXAMINER Hoon K. Song | | | | DATE CONSIDERED 9/30/04 | | | |
| EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | | | | | | | |